

CLAIMS

5 1. Electrostatic micro-switch intended to electrically connect at least two electrically conductive paths placed on a support, the electric connection between the two conductor paths being created by means of a contact stud fitted to the
10 distortion means made in insulating material and capable of distorting in relation to the support, under the influence of an electrostatic force generated by control electrodes, the contact stud electrically connecting the ends of the two conductor paths when the distortion means are sufficiently
15 distorted, wherein the control electrodes are laid out on the distortion means and the support in two sets of electrodes, a first set of electrodes intended to generate a first electrostatic force to initiate the distorting of the distortion means until it creates a mechanical contact with
20 the distortion means, the ends of the conductor paths being sufficiently distanced from each other so that the contact stud does not electrically connect the ends of the conductor paths, a second set of electrodes intended to generate a second electrostatic force to continue the distorting of the
25 distortion means so that the contact stud electrically connects the ends of the two conductor paths.

5 2. Electrostatic micro-switch according to claim 1,
wherein the control electrodes laid out on the distortion
means are placed on the latter so that the distortion means
are interposed between them and the control electrodes laid
out on the support.

10 3. Electrostatic micro-switch according to claim 1,
wherein the control electrodes laid out on the support
comprise two electrodes each of which is a common electrode to
the first set of electrodes and to the second set of
15 electrodes.

 4. Electrostatic micro-switch according to claim 1,
wherein the distortion means comprise a beam embedded at its
two ends or a cantilever beam.

20 5. Electrostatic micro-switch according to claim 4,
wherein the control electrodes laid out on the distortion
means comprise the electrodes of one of the two sets of
electrodes placed on the annex parts attached to the beam and
25 fitted on each side of the beam.

 6. Electrostatic micro-switch according to claim 5,
wherein the control electrodes laid out on the distortion
means comprise the electrodes of the other of the two sets of
30 electrodes placed on the beam and fitted on each side of the
contact stud.